

Burn-Wet Scrubber

Integrated Plasma Inc.

- **Highly efficient Burn/Wet Systems for treatment of all kind of gases, especially for PFC's.**

Abatement Type	ECS-3000S
Scrubber Type	Burn-Wet
Dimensions (mm)	2100W x 1500D x 2005H
Weight	550Kg
Total Flow rate	400LPM
Temperature (For Processing Gas)	1200°C(Up to 1400°C)
Max. No. of Inlet ports	Up to 4
Inlet Port Type option	KF50
Outlet Port Type	1 x ISO100



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Application & DRE :

Target abatement gas

1. PFCs: $\text{NF}_3 > 99\%$, $\text{C}_2\text{F}_6 > 95\%$, $\text{SF}_6 > 95\%$, $\text{CF}_4 > 90\%$, $\text{C}_3\text{F}_8 > 95\%$, etc
2. Flammable gases: $\text{SiH}_4 > 99\%$, $\text{PH}_3 > 99\%$, $\text{TEOS} > 99\%$, $\text{H}_2 > 99\%$, DCS, etc
3. Water soluble gases: Cl_2 , $\text{HCl} > 99\%$, HF, NH_3 , etc
4. Toxic gases: $\text{B}_2\text{H}_6 > 99\%$, $\text{WF}_6 > 99\%$, $\text{TEPO} > 99\%$, $\text{C}_4\text{F}_8 > 95\%$, $\text{TEB} > 99\%$

Process :

Solar 、 Thin Film 、 Etching 、 Diffusion.

The abatement system is highly efficient used in CVD and etch applications for photovoltaic, semiconductor and other related industries.

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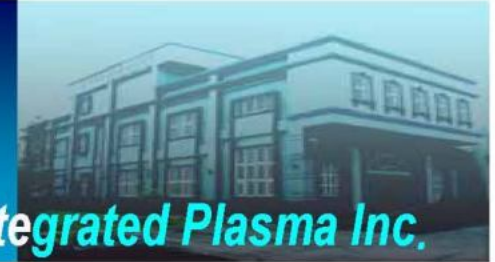
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Advantage:

- High efficient burner washer for low and high waste gas flows.
 - Highest standards of safety to eliminate any risks for operators and environment.
 - Lowest Cost of Ownership through low utility costs and by long maintenance intervals.
 - No risk of corrosion - all pipes are coated inside with corrosion resistant material. No neutralisation agent is necessary.
 - The system operates with city water, no water pre-conditioning is required.
 - Automatic scrapers for mechanical cleaning of reactor and burner prevent blockages allow cleaning without opening the system and reduce the preventive maintenance impact. (Option)
 - Flexible burning gases are possible.
 - High abatement efficiency for PFC gases.
 - Strong recommendation for CVD : good treatment for powder Excellent safety interlocks included flow, temperature, pressure, and leak sensors.
 - Special cooling design to prevent powder accumulation.
 - Relatively lower operation cost.
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Advantage:

- Simple operation and easy maintenance.
 - The advantage of powder trap could be 5um below.
 - High anti-corrosion design.
 - SEMI-S2 certified.
 - Directly handles gas with the combustion method.
 - It has an efficient and compact design.
 - Best possible reduction of nitrogen oxides (NOx) by small amounts of purge gas necessary. That is especially true in combination with dry vacuum pumps with their small amounts of N2 purge required.
 - Various operation modes: high, medium, low and idle operation mode allow to save utilities cost.
 - Lowest Cost of Ownership through low utility costs and by long maintenance intervals.
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Advantage:

- IPI's burner-washers are based on the principle of gas decomposition by combustion. This technology offers the greatest flexibility for exhaust gas abatement for the effluent gases used in Semiconductor, Photovoltaic - Solar, Thin Film, Compound Semiconductor manufacturing industries. It is designed for the abatement of both CVD and etch gases. IPI's burner technology produces high temperatures that allow high abatement efficiencies for the process gases including perfluorinated gases, PFCs.
 - The equipment is ready to operate immediately after the burners are fired on receiving an input command signal from the control panel and needs no pre/standby burning by the combustion reactor. In addition, a unique combustion algorithm is used to maintain fuel gas at the optimum quantity for each type of gas to be treated. Therefore, fuel gas consumption can be reduced.
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